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**IN THE  
UNITED STATES  
PATENT AND TRADEMARK OFFICE**

**IN RE APPLICATION OF:** Kirchner, et al.

**SERIAL NO.:** 10/815,116

**FILED ON:** March 31, 2004

**DOCKET NO.:** OST-041134

**CUSTOMER NO.:** 22876

**RESPONSE TO FINAL  
OFFICE ACTION**

**CONFIRMATION NO.:** 6567

**FOR:** METHOD FOR DISTORTION  
CORRECTION IN A  
MICROLITHOGRAPHIC  
PROJECTION EXPOSURE  
APPARATUS

Box AF  
COMMISSIONER  
FOR PATENTS  
P.O. Box 1450  
Alexandria VA 22313-1450

**ATTENTION OF:** Art Unit 2851

**EXAMINER:** Gutierrez, Kevin C.

Dear Examiner:

In response to the Final Office Action of March 17, 2005, please consider the following:

**Amendments to the Claims** are reflected in the listing that begins on page 2 of this paper.

**Remarks/Arguments** begin on page 7 of this paper.

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